

L Number	Hits	Search Text	DB	Time stamp
1	11	"5012105"	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 13:32
2	3002	(250/492.22,492.2,492.23).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 13:33
3	3501	(250/492.22,492.2,492.23,398).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 13:34
4	8190	multibeam or multi-beam or (multiple adj (aperture or beam or beamlet)) and (electron or charged-particle or (charged adj particle))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 13:36
5	185	((multibeam or multi-beam or (multiple adj (aperture or beam or beamlet)) and (electron or charged-particle or (charged adj particle))) and (beamlet or subbeam or sub-beam))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 13:36
6	112	((multibeam or multi-beam or (multiple adj (aperture or beam or beamlet)) and (electron or charged-particle or (charged adj particle))) and (beamlet or subbeam or sub-beam)) and aperture	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 13:37
7	71	((multibeam or multi-beam or (multiple adj (aperture or beam or beamlet)) and (electron or charged-particle or (charged adj particle))) and (beamlet or subbeam or sub-beam)) and aperture) and deflect\$4	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 13:37
8	10	((multibeam or multi-beam or (multiple adj (aperture or beam or beamlet)) and (electron or charged-particle or (charged adj particle))) and (beamlet or subbeam or sub-beam)) and aperture) and deflect\$4) and (different with pattern)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 13:38
9	46	((multibeam or multi-beam or (multiple adj (aperture or beam or beamlet)) and (electron or charged-particle or (charged adj particle))) and (beamlet or subbeam or sub-beam)) and aperture) and deflect\$4) and simultan\$8	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 13:39
10	33	((multibeam or multi-beam or (multiple adj (aperture or beam or beamlet)) and (electron or charged-particle or (charged adj particle))) and (beamlet or subbeam or sub-beam)) and aperture) and deflect\$4) and simultan\$8) and independent\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 13:45
11	45	((multibeam or multi-beam or (multiple adj (aperture or beam or beamlet)) and (electron or charged-particle or (charged adj particle))) and (beamlet or subbeam or sub-beam)) and aperture) and deflect\$4) and simultan\$8) and (independent\$3 or individual\$4)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 13:52
12	7	((multibeam or multi-beam or (multiple adj (aperture or beam or beamlet)) and (electron or charged-particle or (charged adj particle))) and (beamlet or subbeam or sub-beam)) and aperture) and deflect\$4) and simultan\$8) and (independent\$3 or individual\$4) and ((250/492.22,492.2,492.23,398).CCLS.)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 13:51

13	17	((((multibeam or multi-beam or (multiple adj (aperture or beam or beamlet)) and (electron or charged-particle or (charged adj particle))) and (beamlet or subbeam or sub-beam)) and aperture) and deflect\$4) and simultan\$8) and ((independent\$3 or individual\$4) with deflect\$5)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 13:53
14	9	"5359202"	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 14:01
15	11	"5841145"	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 14:03
16	10	"5977548"	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 14:04

L Number	Hits	Search Text	DB	Time stamp
1	556	((multiple adj (beam or aperture)) or multibeam or multi-beam) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:37
2	31	((multiple adj (beam or aperture)) or multibeam or multi-beam) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (beamlet or subbeam or sub-beam)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:38
3	26	((multiple adj (beam or aperture)) or multibeam or multi-beam) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (beamlet or subbeam or sub-beam)) and (different\$4 near4 (imag\$5 or pattern\$4))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:38
4	24	((multiple adj (beam or aperture)) or multibeam or multi-beam) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (beamlet or subbeam or sub-beam)) and (different\$4 near4 (imag\$5 or pattern\$4))) and (independent\$3 or individual\$4) and deflect\$5	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:38
5	19	((multiple adj (beam or aperture)) or multibeam or multi-beam) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (beamlet or subbeam or sub-beam)) and (different\$4 near4 (imag\$5 or pattern\$4))) and (independent\$3 or individual\$4) and deflect\$5) and (etch\$3 or writing or lithograph\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:05
6	353	((multiple adj (beam or aperture)) or multibeam or multi-beam) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (different\$4 near4 (imag\$5 or pattern\$4))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:05
7	162	((multiple adj (beam or aperture)) or multibeam or multi-beam) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (different\$4 near4 (imag\$5 or pattern\$4))) and (independent\$3 or individual\$4) and deflect\$5	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:06
8	118	((multiple adj (beam or aperture)) or multibeam or multi-beam) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (different\$4 near4 (imag\$5 or pattern\$4))) and (independent\$3 or individual\$4) and deflect\$5) and (etch\$3 or writing or lithograph\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:39
9	32	((multiple adj (beam or aperture)) or multibeam or multi-beam) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (different\$4 near4 (imag\$5 or pattern\$4))) and (independent\$3 or individual\$4) and deflect\$5) and (etch\$3 or writing or lithograph\$3)) and ((independent\$3 or individual\$4) with deflect\$5)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:39

10	0	09/375627	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:28
11	0	(09/375627).CCLS.	USPAT; US-PGPUB; EPO; DERWENT; IBM_TDB	2003/10/17 16:28
12	7	"375627"	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:28
13	2	Hans adj Loschner	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:29
14	2	5637951.URPN.	USPAT	2003/10/17 16:34
15	6	("4675572" "4940916" "4990766" "5103144" "5363021" "5528103").PN.	USPAT	2003/10/17 16:35
16	606	((multiple adj (beam or aperture)) or multibeam or multi-beam or multi-electron or multielectron) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:37
17	31	((multiple adj (beam or aperture)) or multibeam or multi-beam or multi-electron or multielectron) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (beamlet or subbeam or sub-beam)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:38
18	380	((multiple adj (beam or aperture)) or multibeam or multi-beam or multi-electron or multielectron) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (different\$4 near4 (imag\$5 or pattern\$4))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:38
19	171	((multiple adj (beam or aperture)) or multibeam or multi-beam or multi-electron or multielectron) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (different\$4 near4 (imag\$5 or pattern\$4))) and (independent\$3 or individual\$4) and deflect\$5	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:38
20	127	((multiple adj (beam or aperture)) or multibeam or multi-beam or multi-electron or multielectron) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (different\$4 near4 (imag\$5 or pattern\$4))) and (independent\$3 or individual\$4) and deflect\$5) and (etch\$3 or writing or lithograph\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:39

21	39	((((multiple adj (beam or aperture)) or multibeam or multi-beam or multi-electron or multielectron) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (different\$4 near4 (imag\$5 or pattern\$4))) and (independent\$3 or individual\$4) and deflect\$5) and (etch\$3 or writing or lithograph\$3)) and ((independent\$3 or individual\$4) with deflect\$5)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:39
22	34	((((multiple adj (beam or aperture)) or multibeam or multi-beam or multi-electron or multielectron) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (different\$4 near4 (imag\$5 or pattern\$4))) and (independent\$3 or individual\$4) and deflect\$5) and (etch\$3 or writing or lithograph\$3)) and ((independent\$3 or individual\$4) with deflect\$5)) and aperture	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:49

L Number	Hits	Search Text	DB	Time stamp
1	556	((multiple adj (beam or aperture)) or multibeam or multi-beam) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:37
2	31	((multiple adj (beam or aperture)) or multibeam or multi-beam) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (beamlet or subbeam or sub-beam)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:38
3	26	((multiple adj (beam or aperture)) or multibeam or multi-beam) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (beamlet or subbeam or sub-beam)) and (different\$4 near4 (imag\$5 or pattern\$4))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:38
4	24	((multiple adj (beam or aperture)) or multibeam or multi-beam) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (beamlet or subbeam or sub-beam)) and (different\$4 near4 (imag\$5 or pattern\$4))) and (independent\$3 or individual\$4) and deflect\$5	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:38
5	19	((multiple adj (beam or aperture)) or multibeam or multi-beam) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (beamlet or subbeam or sub-beam)) and (different\$4 near4 (imag\$5 or pattern\$4))) and (independent\$3 or individual\$4) and deflect\$5) and (etch\$3 or writing or lithograph\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:05
6	353	((multiple adj (beam or aperture)) or multibeam or multi-beam) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (different\$4 near4 (imag\$5 or pattern\$4))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:05
7	162	((multiple adj (beam or aperture)) or multibeam or multi-beam) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (different\$4 near4 (imag\$5 or pattern\$4))) and (independent\$3 or individual\$4) and deflect\$5	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:06
8	118	((multiple adj (beam or aperture)) or multibeam or multi-beam) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (different\$4 near4 (imag\$5 or pattern\$4))) and (independent\$3 or individual\$4) and deflect\$5) and (etch\$3 or writing or lithograph\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:39
9	32	((multiple adj (beam or aperture)) or multibeam or multi-beam) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (different\$4 near4 (imag\$5 or pattern\$4))) and (independent\$3 or individual\$4) and deflect\$5) and (etch\$3 or writing or lithograph\$3)) and ((independent\$3 or individual\$4) with deflect\$5)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:39

10	0	09/375627	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:28
11	0	(09/375627).CCLS.	USPAT; US-PGPUB; EPO; DERWENT; IBM_TDB	2003/10/17 16:28
12	7	"375627"	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:28
13	2	Hans adj Loschner	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:29
14	2	5637951.URPN.	USPAT	2003/10/17 16:34
15	6	("4675572" "4940916" "4990766" "5103144" "5363021" "5528103").PN.	USPAT	2003/10/17 16:35
16	606	((multiple adj (beam or aperture)) or multibeam or multi-beam or multi-electron or multielectron) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:37
17	31	((multiple adj (beam or aperture)) or multibeam or multi-beam or multi-electron or multielectron) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (beamlet or subbeam or sub-beam)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:38
18	380	((multiple adj (beam or aperture)) or multibeam or multi-beam or multi-electron or multielectron) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (different\$4 near4 (imag\$5 or pattern\$4))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:38
19	171	((multiple adj (beam or aperture)) or multibeam or multi-beam or multi-electron or multielectron) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (different\$4 near4 (imag\$5 or pattern\$4))) and (independent\$3 or individual\$4) and deflect\$5	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:38
20	127	((multiple adj (beam or aperture)) or multibeam or multi-beam or multi-electron or multielectron) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (different\$4 near4 (imag\$5 or pattern\$4))) and (independent\$3 or individual\$4) and deflect\$5) and (etch\$3 or writing or lithograph\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:39

21	39	((((multiple adj (beam or aperture)) or multibeam or multi-beam or multi-electron or multielectron) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (different\$4 near4 (imag\$5 or pattern\$4))) and (independent\$3 or individual\$4) and deflect\$5) and (etch\$3 or writing or lithograph\$3)) and ((independent\$3 or individual\$4) with deflect\$5)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:39
22	34	((((multiple adj (beam or aperture)) or multibeam or multi-beam or multi-electron or multielectron) and (electron or charged-particle or (charged adj particle)) and (different\$4 with (imag\$5 or pattern\$4))) and (different\$4 near4 (imag\$5 or pattern\$4))) and (independent\$3 or individual\$4) and deflect\$5) and (etch\$3 or writing or lithograph\$3)) and ((independent\$3 or individual\$4) with deflect\$5)) and aperture	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 16:49

L Number	Hits	Search Text	DB	Time stamp
1	1966	(multibeam or multibeam or multi-aperture or multi-aperture or (multiple adj beam)) and simultaneous\$3 and pattern\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 18:25
2	696	((multibeam or multibeam or multi-aperture or multi-aperture or (multiple adj beam)) and simultaneous\$3 and pattern\$3) and ((different or var\$5) near4 (pattern\$4 or imag\$5))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 17:58
3	449	((multibeam or multibeam or multi-aperture or multi-aperture or (multiple adj beam)) and simultaneous\$3 and pattern\$3) and ((different or var\$5) near4 (pattern\$4 or imag\$5))) and aperture	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 17:59
4	627	((multibeam or multibeam or multi-aperture or multi-aperture or (multiple adj beam)) and simultaneous\$3 and pattern\$3) and ((different or var\$5) near4 (pattern\$4 or imag\$5))) and (individual\$4 or independent\$4)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 18:01
5	30	114 and (etch\$4 or writing)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 18:01
6	2905	(multibeam or multibeam or multi-aperture or multi-aperture or (multiple adj beam)) and simultaneous\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 18:15
7	268	((multibeam or multibeam or multi-aperture or multi-aperture or (multiple adj beam)) and simultaneous\$3) and lithograph\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 18:04
8	180	((multibeam or multibeam or multi-aperture or multi-aperture or (multiple adj beam)) and simultaneous\$3) and lithograph\$3) and (electron or ion or charged-particle or (charged adj particle))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 18:06
9	830	((multibeam or multibeam or multi-aperture or multi-aperture or (multiple adj beam)) and simultaneous\$3) and (electron or ion or charged-particle or (charged adj particle))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 18:06
10	165	(multibeam or multibeam or multi-aperture or multi-aperture or (multiple adj beam)) and ((etch\$4 or writ\$4) near4 (different or vari\$5))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 18:11
11	830	(multibeam or multibeam or multi-aperture or multi-aperture or (multiple adj beam)) and simultaneous\$3 and (electron or ion or charged-particle or (charged adj particle))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 18:20
12	744	((multibeam or multibeam or multi-aperture or multi-aperture or (multiple adj beam)) and simultaneous\$3 and (electron or ion or charged-particle or (charged adj particle))) and different	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 18:21
14	0	((multibeam or multibeam or multi-aperture or multi-aperture or (multiple adj beam)) and simultaneous\$3 and (electron or ion or charged-particle or (charged adj particle))) and different) and pattern\$3) and aberration	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 18:22

13	549	((mulitbeam or mulit-beam or multi-aperture or multi-aperture or (multiple adj beam)) and simultaneous\$3 and (electron or ion or charged-particle or (charged adj particle))) and different) and pattern\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 18:22
15	402	(mulitbeam or mulit-beam or multi-aperture or multi-aperture or (multiple adj beam)) and simultaneous\$3 and (different near2 (image or pattern\$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 18:28
16	9	((mulitbeam or mulit-beam or multi-aperture or multi-aperture or (multiple adj beam)) and simultaneous\$3 and (different near2 (image or pattern\$3))) and ((writ\$3 or etch\$4) with(different near2 (image or pattern\$3)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/10/17 18:29